

USSN 10/676,414

### AMENDMENTS TO SPECIFICATION

[0024] The nucleation sites 58 may be protrusions from the data layers 54 or ~~divets-divots~~ in the data layers 54. The shape of the ~~divets-divots~~ or protrusions may be circular, elliptical, rectangular, or any other shape.

[0026] The nucleation sites 58 may be as thick as, or thicker than, the data layer 54. Thus the protrusions may be as thick as the data layer 54, and the ~~divets~~ divots may extend through the data layer 54

[0028] The data layers 54 are not limited to the nucleation sites 58 shown in Figure 4. Other type and arrangements of nucleation sites are shown in Figures 5a-5f. Figures 5a, 5b, 5c 5f show that the nucleation sites 58 may be protrusions instead of ~~divets~~ divots, Figures 5b-5f shows that a data layer 54 may have more than one nucleation site 58; and Figures 5b, 5e and 5f show that two nucleation sites 58 may be formed at different edges

[0032] Bits are formed (116). Lithography (e.g., photolithography, e-beam lithography) may be used to define a pattern on the stack, and bits may be formed by a process such as ion milling, chemical etching, drying etching, etc. The patterns include the definitions of the nucleation sites. Thus the nucleation sites (e.g., protrusions, ~~divets~~ divots) are formed during formation of the bits.